AMENDMENT UNDER 37 C.F.R. § 1.116 EXPEDITING PROCEDURE EXAMINING GROUP 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Van Beek, et al. Docket No.: EPC-019

Serial No.: 10/578,026 Art Unit: 2829

Filed: March 13, 2007 Examiner: Karen M. Kusumakar

Conf. No.: 4725

For: Method of Manufacturing a MEMS Device and MEMS Device

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR § 1.116

Dear Sir:

Applicant respectfully submits the following amendments and remarks in response to Examiner's Office Action dated March 5, 2009, which Action is made final. Applicant respectfully requests that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of the claims.

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